

35.C13974 D1

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
TADAHIRO OHMI, ET AL.) Examiner: Not Yet Assigned
Divisional of)
Application No.: 09/425,015) Group Art Unit: N.Y.A.
Filed: Herewith)
For: EXPOSURE APPARATUS, AND)
DEVICE PRODUCTION METHOD) November 5, 2001
(As Amended)

Commissioner for Patents
Washington, D.C. 20231

PRELIMINARY AMENDMENT

Sir:

Prior to examination on the merits, please amend the above-identified application as follows:

IN THE TITLE:

Please delete "GAS SUPPLY PATH STRUCTURE, GAS SUPPLY METHOD, LASER OSCILLATING APPARATUS, EXPOSURE APPARATUS, AND DEVICE PRODUCTION METHOD" and insert --EXPOSURE APPARATUS, AND DEVICE PRODUCTION METHOD".

IN THE SPECIFICATION:

Page 1, line 2, insert the following new paragraph:

CONTINUING DATA

This application is a division of Application No. 09/425,015, filed October 25, 1999, pending.

IN THE CLAIMS:

Please cancel claims 1-40 without prejudice or disclaimer.

REMARKS

This is a division of Application No. 09/425,015 filed October 25, 1999, which is still pending.

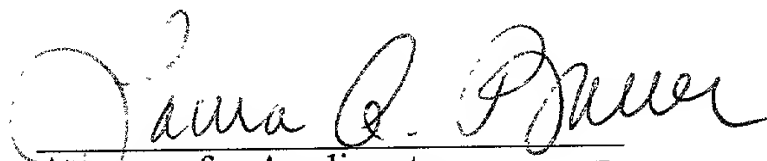
In response to a Written Restriction Requirement in the parent application, Applicants elected claims 1-40 for prosecution.

This divisional application is filed to pursue the subject matter of the non-elected claims 41-44.

Early consideration of the claims presented in this Preliminary Amendment and issuance of Notice of Allowance are earnestly requested.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below.

Respectfully submitted,


Attorney for Applicants
Registration No. 841767

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